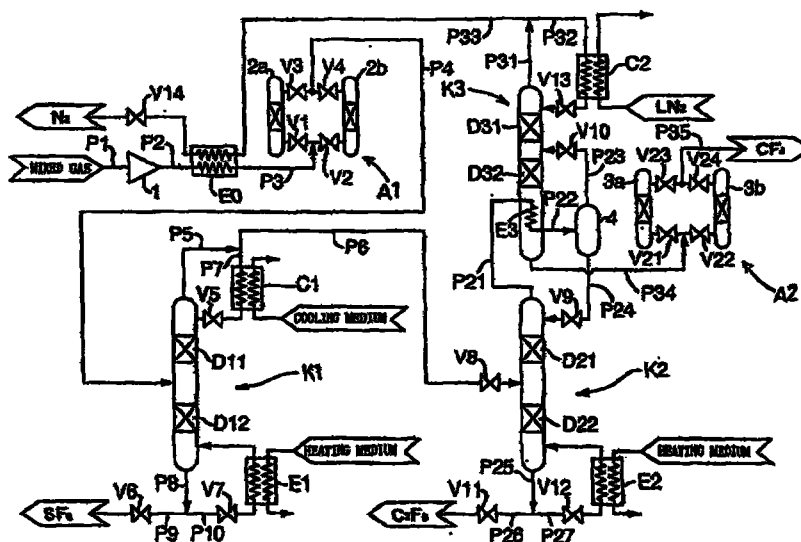




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(54) Title: PROCESS FOR SEPARATING AND PURIFYING FLUORINE COMPOUNDS, AND INSTALLATION THEREOF



(57) Abstract

There are provided a process for separating and purifying fluorine compounds, in which a proper rectifying operation of a mixed gas can be carried out even when it contains methane trifluoride, whereby fluorine compound components contained in the mixed gas can be separated and purified up to such concentrations as they can be reutilized, and further an installation therefor. In a process for separating and purifying fluorine compounds, in which from a mixed gas containing plural fluorine compounds a part of or all of these respective components is separated and purified by use of rectification units, methane trifluoride is previously separated and removed from said mixed gas containing methane trifluoride by an adsorption unit (A1), and then a part of or all of the remaining components is separated in turn through rectification by said rectification units (K1, K2, K3).